

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re Application of : Customer Number: 20277  
 :  
 Masashi HAMANAKA, et al. : Confirmation Number: 8488  
 :  
 Application No.: 10/671,502 : Group Art Unit: 3723  
 :  
 Filed: September 29, 2003 : Examiner: MAURINA T. RACHUBA  
 :

For: POLISHING METHOD FOR SEMICONDUCTOR DEVICE, METHOD FOR FABRICATING SEMICONDUCTOR DEVICE AND POLISHING SYSTEM

Mail Stop Amendment  
 Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

Dear Sir:

Transmitted herewith is an Amendment in the above-identified application.

- ☒ No additional fee is required.  
☐ Applicant is entitled to small entity status under 37 CFR 1.27  
☐ Also attached:

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	11	21	0	\$50.00 =	\$0.00
Independent Claims	6	7	0	\$200.00 =	\$0.00
Multiple dependent claims newly presented					\$0.00
Fee for extension of time					\$0.00
					\$0.00
Total of Above Calculations					\$0.00

- ☐ Please charge my Deposit Account No. 500417 in the amount of \$0.00. An additional copy of this transmittal sheet is submitted herewith.
- ☒ The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

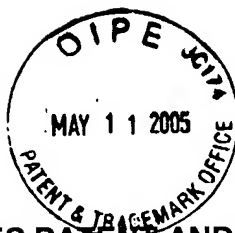
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Please recognize our Customer No. 20277 as our correspondence address.

Attorney Docket No.: 60188-658



PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of :  
Masashi HAMANAKA, et al. : Customer No.20277  
Serial No.: 10/671,502 : Confirmation No.: 8488  
Filed: September 29, 2003 : Group Art Unit: 3723  
For: POLISHING METHOD FOR SEMICONDUCTOR DEVICE, METHOD FOR : Examiner: MAURINA T. RACHUBA  
FABRICATING SEMICONDUCTOR DEVICE AND POLISHING SYSTEM

**ELECTION UNDER 35 U.S.C. § 121  
AND PRELIMINARY AMENDMENT**

Mail Stop Amendment  
Hon. Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the restriction requirement set forth in the Office Action mailed April 11, 2005, having a shortened statutory period for response set to expire May 11, 2005, wherein the Examiner required restriction between the following distinct Species:

- Species 1 - Figure 3, the use of a filter;
- Species 2 - Figure 5, the use of a vinyl chloride type tube; and
- Species 3 - Figure 11, the use of a two layer tube, of vinyl chloride and rubber.;

Applicants elect Species 2, with claims 7-10 readable thereon, for initial prosecution on the merits.